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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/743,276 12/23/2003		Noud Jan Gilissen	081468-0307180	4466	_
909 7.	590 01/05/2005		EXAMINER		
PILLSBURY P.O. BOX 1050	WINTHROP, LLP	BERMAN, JACK I			
MCLEAN, VA 22102			ART UNIT	PAPER NUMBER	1
		2881			
		DATE MAILED: 01/05/2005			

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application	n No	Applicant(s)				
Office Action Summary				GILISSEN ET AL.				
		10/743,27	··					
	,	Examiner		Art Unit				
	The MAILING DATE of this commun	Jack I. Bei		2881	Idrocc			
Period fo		cauon appears on me	Cover Sheet with the t	orrespondence ad	10/635			
THE - External after - If the - If NC - Failu Any (ORTENED STATUTORY PERIOD FOR MAILING DATE OF THIS COMMUNI asions of time may be available under the provisions SIX (6) MONTHS from the mailing date of this common period for reply specified above is less than thirty (3) apperiod for reply is specified above, the maximum stare to reply within the set or extended period for reply reply received by the Office later than three months and patent term adjustment. See 37 CFR 1.704(b).	CATION. of 37 CFR 1.136(a). In no evenunication. O) days, a reply within the statuatutory period will apply and wiwill, by statute, cause the apply.	ent, however, may a reply be tin story minimum of thirty (30) day Il expire SIX (6) MONTHS from ication to become ABANDONE	nely filed s will be considered timel the mailing date of this c D (35 U.S.C. § 133).				
Status								
1)	Responsive to communication(s) file	d on						
2a)	This action is FINAL .	2b)⊠ This action is n	on-final.					
3)□	-							
Dispositi	on of Claims							
5)⊠	<u></u>							
Applicati	on Papers							
9) ☐ The specification is objected to by the Examiner. 10) ☑ The drawing(s) filed on 23 December 2003 is/are: a) ☑ accepted or b) ☐ objected to by the Examiner. Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a). Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d). 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.								
Priority u	ınder 35 U.S.C. § 119							
12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received.								
Attachmen								
1) Notice	e of References Cited (PTO-892) e of Draftsperson's Patent Drawing Review (P	TO 048)	4) Interview Summary Paper No(s)/Mail D					
3) 🔯 Infor	te of Dransperson's Patent Drawing Review (Pmation Disclosure Statement(s) (PTO-1449 or r No(s)/Mail Date <u>5/28/04</u> .			Patent Application (PT	O-152)			

The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

Claim 13 is rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. The specification and drawings clearly indicate that it is "one of the *patterning device* and the substrate" that is held on the pimple plate during operation of the lithographic projection apparatus, not "one of the *patterned beam* and the substrate" as is claimed in line 8 of the claim. A beam of radiation cannot be held on a plate.

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

Claim 15 is rejected under 35 U.S.C. 102(b) as being anticipated by Kendall. Kendall discloses a holding means (the electrostatic chuck part of Kendall's membrane electrostatic chuck 32) for holding at least one of a patterning device and a substrate in a lithographic projection apparatus that comprises means for projecting a patterned beam of radiation onto a target portion of a substrate (see lines 35-45 in column 4) and means (the membrane part of Kendall's membrane electrostatic chuck 32) for resiliently supporting said holding means. While Kendall does not explicitly describe the lithographic projection apparatus, the use of the disclosed holding means for its disclosed purpose inherently requires such lithographic projection apparatus.

Claims 1-12, 15, and 16 are allowed.

Application/Control Number: 10/743,276

Art Unit: 2881

Claim 13 would be allowable if rewritten or amended to overcome the rejection(s) under 35 U.S.C. 112, 2nd paragraph, set forth in this Office action.

Page 3

The following is a statement of reasons for the indication of allowable subject matter: While pimple plates are known in the art for holding either patterning devices or substrates (see, for example, U.S. Patent No. 5,656,093 to Burkhart et al., cited in the Information Disclosure Statement filed on May 28, 2004), there is no suggestion in the prior art to use such a pimple

plate support chuck as the chuck component of Kendall's membrane electrostatic chuck.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Jack I. Berman whose telephone number is (571) 272-2468. The examiner can normally be reached on M-F (8:30-6:00) with every second Friday off.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, John R. Lee can be reached on (571) 272-2477. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

gack d. Berman Jack I. Berman

Primary Examiner
Art Unit 2881

jb 12/30/04